

PATENT

Atty. Dkt. No. APPM/008244/DSM/BCVD/JW

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Wang et al.

Serial No.: 10/799,146

Confirmation No.: 7933

Filed: March 12, 2004

For: Method of Depositing an  
Amorphous Carbon Film for Etch  
Hardmask Application

§ Group Art Unit: 2812

§ Examiner: Monica D. Harrison

MAIL STOP: AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

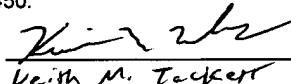
Dear Sir:

CERTIFICATE OF MAILING  
37 CFR 1.8

I hereby certify that this correspondence is being deposited on  
March 27, 2006 with the United States Postal Service as First  
Class Mail in an envelope addressed to: Mail Stop  
Amendment, Commissioner for Patents, P.O. Box 1450,  
Alexandria, VA 22313-1450.

March 27, 2006

Date

  
Keith M. Tackert

**RESPONSE TO OFFICE ACTION DATED DECEMBER 29, 2005**

In response to the Office Action dated December 29, 2005, having a shortened statutory period for response set to expire on March 29, 2006, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicant believes that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008244/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Claims** are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 8 of this paper.